

AMENDMENTS TO THE CLAIMS:

Please cancel claims 1 – 16 and 21 – 24, without prejudice or disclaimer of their subject matter, and amend claim 17 as set forth below.

This listing of claims will replace all prior versions and listings of claims in the application:

1. – 16. (Canceled)

17. (Currently Amended) A deposition apparatus comprising:
a dropping nozzle for supplying dropping a liquid medicine substrate to be processed;
a driving section for moving the substrate and the dropping nozzle relative to each other
to change a dropping point of the substrate; and
a temperature controller on which the substrate is mounted, for providing a temperature distribution from a dropping starting portion point of the substrate to a dropping ending portion point thereof, and setting a temperature at the dropping starting point of the substrate higher than a temperature at the dropping ending point of the substrate.

18. (Original) The deposition apparatus according to claim 17, wherein the temperature controller includes:

a heat absorbing section for absorbing heat and a heat generating section for generating heat, each of the heat absorbing section and the heat generating section being constituted of a plurality of plates whose temperatures are controlled independently; and
a thermal diffusion plate provided on the heat absorbing section and the heat generating section.

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19. (Original) The deposition apparatus according to claim 17, wherein the temperature controller includes:

a plurality of outer plates for independently controlling temperatures of a plurality of areas of an outer region of the substrate;

a central plate for controlling a temperature of a central region of the substrate;

a thermal diffusion plate provided on the outer plates and the central plate; and

a gap adjustment table which is provided on the thermal diffusion plate and on which the substrate is mounted to form a gap between the thermal diffusion plate and the substrate.

20. (Original) The deposition apparatus according to claim 17, wherein the temperature controller includes:

a plurality of outer plates for independently controlling temperatures of a plurality of areas of an outer region of the substrate;

a thermal diffusion plate provided on the outer plates and a central plate; and

a gap adjustment table which is provided on the thermal diffusion plate and on which the substrate is mounted to form a gap between the thermal diffusion plate and the substrate.

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